EAST Search History

EAST Search History (Interference)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L10	9	((detect$3 sens$3) near3 (immersion liquid fluid water) near3 (during parallel "same" adj time together simultaneous$2) near3 (expos$3 pattern$3 project $3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L11	49	((detect$3 sens$3) near1 (immersion liquid fluid water) near2 (expos$3 pattern$3 project $3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L12	23	((detect$3 sens$3) near3 (immersion liquid fluid water) and (detect$3 sens $3) near3 (during parallel "same" adj time together simultaneous$2) near3 (expos$3 pattern$3 project $3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32
L13	517	((detect$3 sens$3) near3 (during parallel "same" adj time together simultaneous$2) near3 (expos$3 pattern$3 project $3)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:32

L14	1	((detect$3 sens$3) near3 (immersion liquid fluid water) same (load$3 unload$3) near2 (wafer substrate workpiece) and ($5lithograph$2 exposure)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L15	14	((detect$3 sens$3) near3 (immersion liquid fluid water) and (load$3 unload $3) near2 (wafer substrate workpiece) and ($5lithograph$2 exposure)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L16	28	((detect$3 sens$3) near3 (immersion liquid fluid water) and (load$3 unload $3) near2 (wafer substrate workpiece)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L17	0	((detect$3 sens$3) near (immersion liquid fluid water) with (table support chuck holder) same3 (load$3 unload$3) near (wafer substrate workpiece) with (table support chuck holder)). clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33

L18	0	((detect$3 sens$3 camera determin$5) near3 (residual remain$3 leftover undesir$4 unwanted stray leak$3) near (immersion liquid fluid water) and (load$3 unload$3) near (wafer substrate workpiece) with (table support chuck holder)). clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L19	0	((detect$3 sens$3) near (immersion liquid fluid water) with (table support chuck holder) and (load$3 unload$3) near (wafer substrate workpiece) with (table support chuck holder)). clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33
L20	0	((detect$3 sens$3) near (immersion liquid fluid water) with (table support chuck holder) and (load$3 unload$3) near (wafer substrate workpiece)).clm.	US-PGPUB; UPAD	OR	ON	2010/12/17 10:33

12/17/2010 10:36:07 AM
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